

J1046 U.S. Pat. & Tm. Off. 10/06/987

U.S. UTILITY Patent Application

						PATENT NUMBER and ISSUE DATE
APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER	<i>Reeves</i>
10084987	02/28/2002	356		2877		
APPLICANTS: Stirton James; Lensing Kevin; Nariman Hormuzdiar; Reeves Steven;						
CONTINUING DATA VERIFIED:						
FOREIGN APPLICATIONS VERIFIED:						
PG-PUB	<input checked="" type="checkbox"/> DO NOT PUBLISH		<input type="checkbox"/> RESCIND			
Foreign priority claimed			<input type="checkbox"/> yes	<input type="checkbox"/> no	ATTORNEY DOCKET NO	
35 USC 119 conditions met			<input type="checkbox"/> yes	<input type="checkbox"/> no	2000.092400	
Verified and Acknowledged Examiners's initials						
TITLE : Method of using high yielding spectra scatterometry measurements to control semiconductor manufacturing processes, and systems for accomplishing same						
U.S. DEPT. OF COMM./PAT. & TM-PTO-436L (Rev. 12-94)						

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED		
			Total Claims		Print Claim for O.G
ISSUE FEE		Primary Examiner	DRAWING		
Amount Due	Date Paid		Sheet(s) Drawn	Fig(s) Drawn	Print Fig.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE			Application Examiner
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